

Title (en)

Methods of fabricating static interferometric display devices and devices formed by same

Title (de)

Verfahren zum Herstellen von interferometrischen Anzeigevorrichtungen und Anzeigen, die damit gebildet werden

Title (fr)

Procédés de fabrication de dispositifs d'affichage interférométriques et dispositifs formés par celui-ci

Publication

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Application

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Abstract (en)

Methods of fabricating static interferometric display devices and devices formed by the same are disclosed. In one embodiment, a static interferometric display device is fabricated by laminating a front substrate and a backplate, each of which has components preformed thereon. At least one of the front substrate and the backplate has cavities of selected depth for interferometric modulation. Features are formed by deposition and patterning, by embossing, or by patterning and etching. The methods not only reduce the manufacturing costs, but also provide a higher yield.

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